TRANSFER DEVICE AND EXHAUST METHOD

ABSTRACT

A transfer device for loading and unloading substrates to and from a processing apparatus that processes the substrates includes a main body including a transfer space in which a transfer robot for transferring the substrates is provided, and a storage space connected to the transfer space and configured to support the substrates. The main body further includes: a housing constituting the transfer space, the housing including a wall configured to form a front surface to which a load port configured to support a container for accommodating the substrates is connected, a rear surface to which a load lock provided in the processing apparatus is connected, and a pair of side surfaces connecting the front surface and the rear surface in a device depth direction, and a column connected to the wall; and an exhaust passage configured to discharge a gas supplied to the storage space. The exhaust passage is formed within the column of the housing.

(Fig. 4)